

The improved FD1 XA assembly: summary of the results and discussion on the proposed changes

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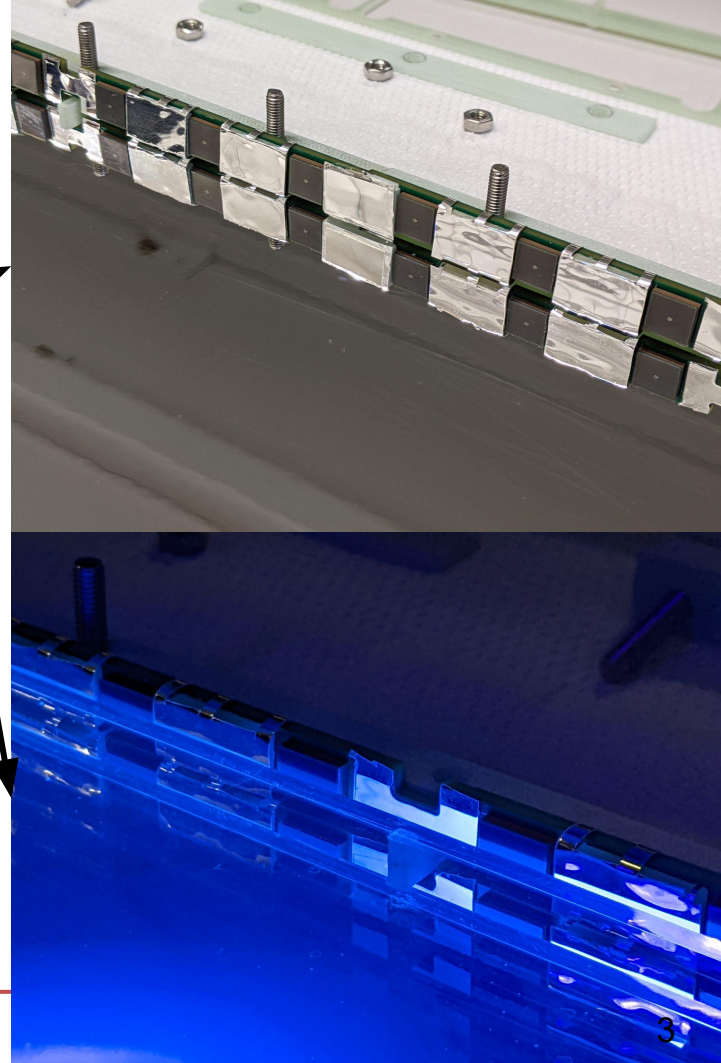
HD-XA Supercell PDE: simulations & measurements

- optical simulation to study **PDE dependence** on:
 - light guide edge - SiPM (Vikuiti) **distance**
 - different **light guide configurations**
 - WLS dye concentration (**attenuation length**)
- **measurements** from January to May with **increased light sealing**:
 - tested different configurations varying:
 - **light sealing**
 - **light guide width**
 - **light guide geometry**
 - one last “control” measurement with the baseline configuration

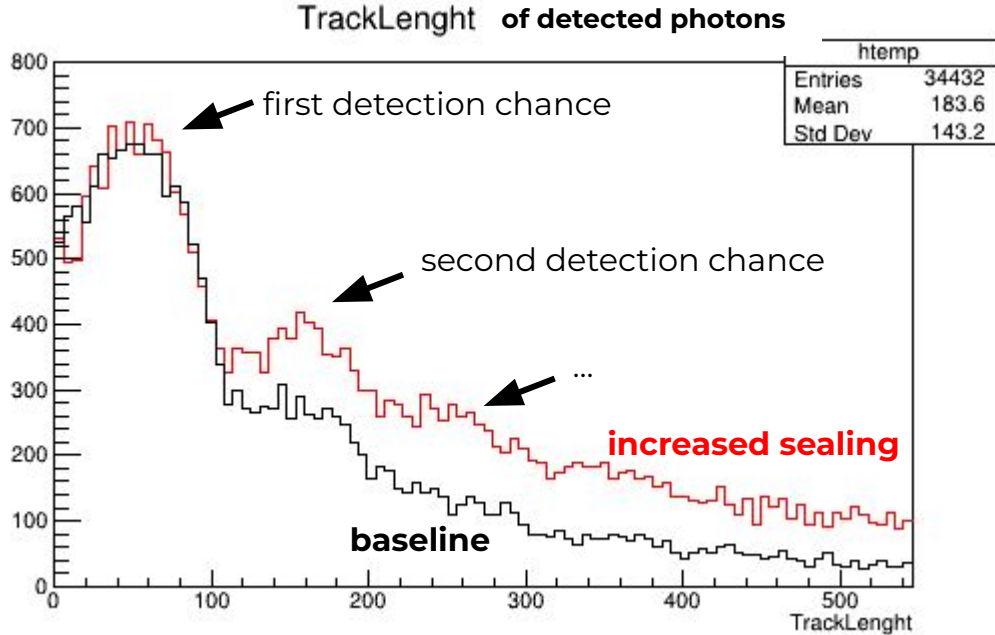
Light sealing

- FD1-XA Supercell with Vikuiti-covered G10 spacer blocks between all the SiPMs; Vikuiti also covers the screw holes
 - placing Vikuiti closer to the light guide provides better light sealing
 - could be the cause of the better PDE of the SBND version
- Tested an “extreme” config.: Vikuiti on three sides (2 x short + 1 x long) edges of the WLS bar.
 - half the SiPMs are partially “blinded”: to check the effect of extreme sealing
 - increase dependence on the WLS-LG

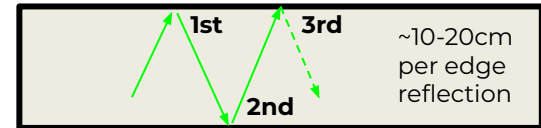
I_{att}



Photon optical path in the module - increased light sealing



- plot of the optical path of **detected photons**
 - “track length” between photon generation (lg WLS process 350->450nm) and detection in a SiPM
- **peaks correspond to photons reaching an edge** instrumented with SiPM and being detected

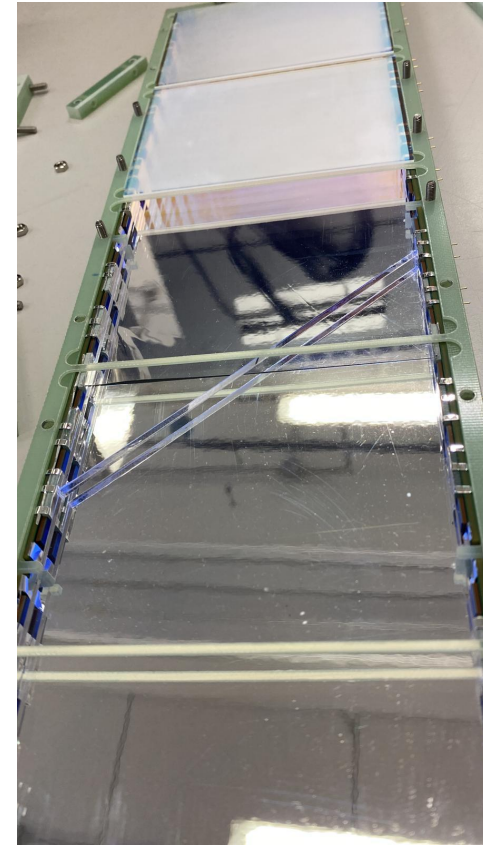
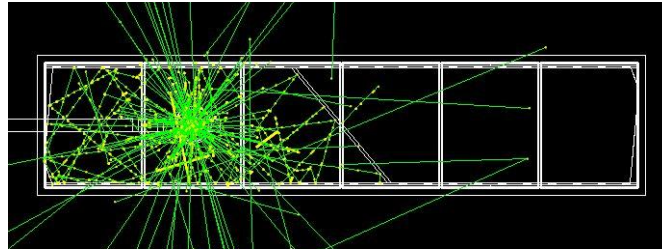
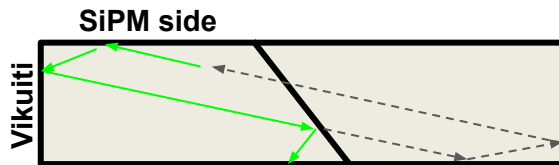


- at the **first chance the two configurations are equal** since the SiPM surface is the same
- from the second chance increasing light sealing provides an improvement since:
 - with **Vikuiti close** to the light guide, the **photons are reflected to the other edge**
 - with **distant Vikuiti** photons **can escape the light guide**

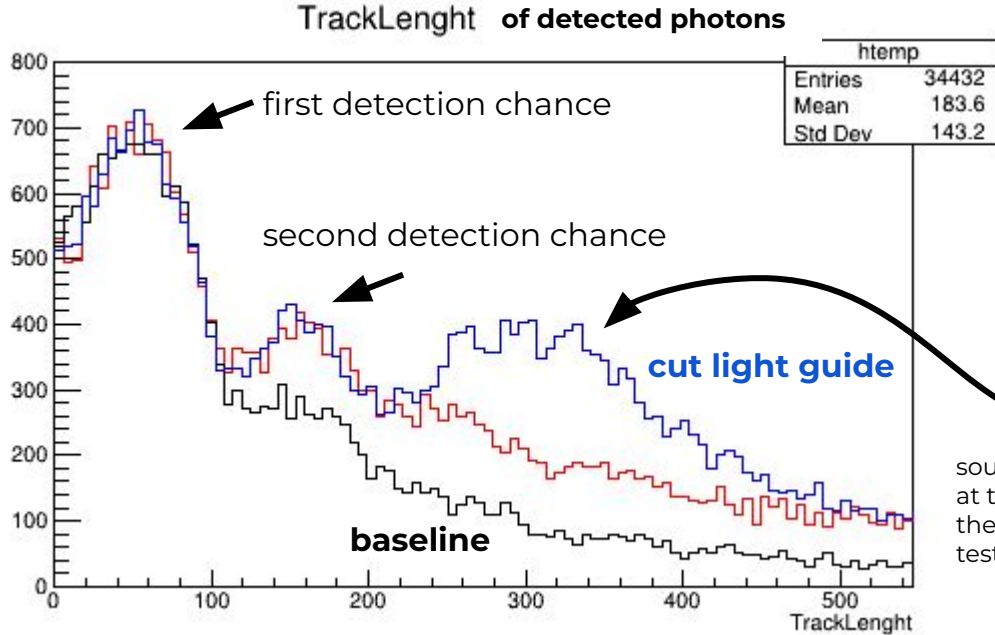
light guide configurations

A different LG geometry should improve the PDE

- cutting the LG with an angle (about 40°)
 - breaks OP bouncing at the shorter edge
 - reflects light to the SiPMs
 - decreases the distance light has to travel to reach a SiPM
- simulated configurations:
 - **2 piece WLS, one 40° cut at the center**

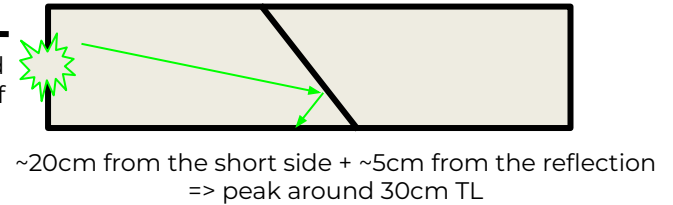


Photon optical path in the module - new geometry



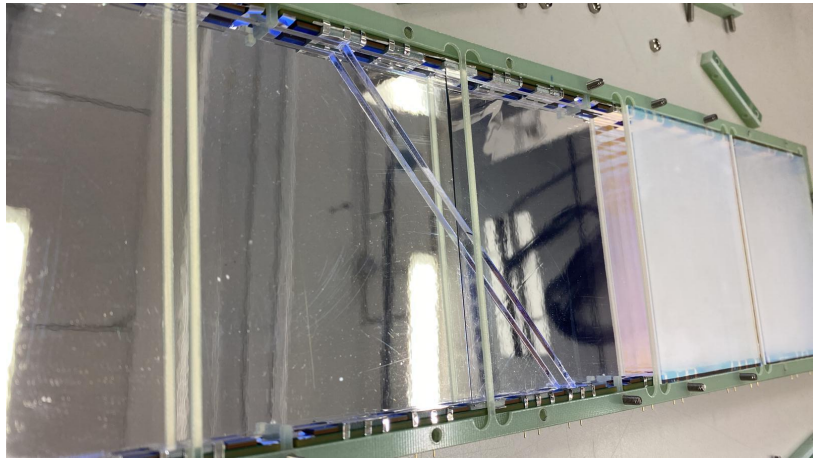
- plot of the optical path of **detected photons**
 - “track length” between photon generation (lg WLS process 350->450nm) and detection in a SiPM
- **the new peak is given by photons emitted towards the short sides reflected at the center**

source placed at the edge of the SC in this test



- the **reflective surface placed at 40°** in the middle of the light guide allows to **detect photons emitted towards the module short sides**

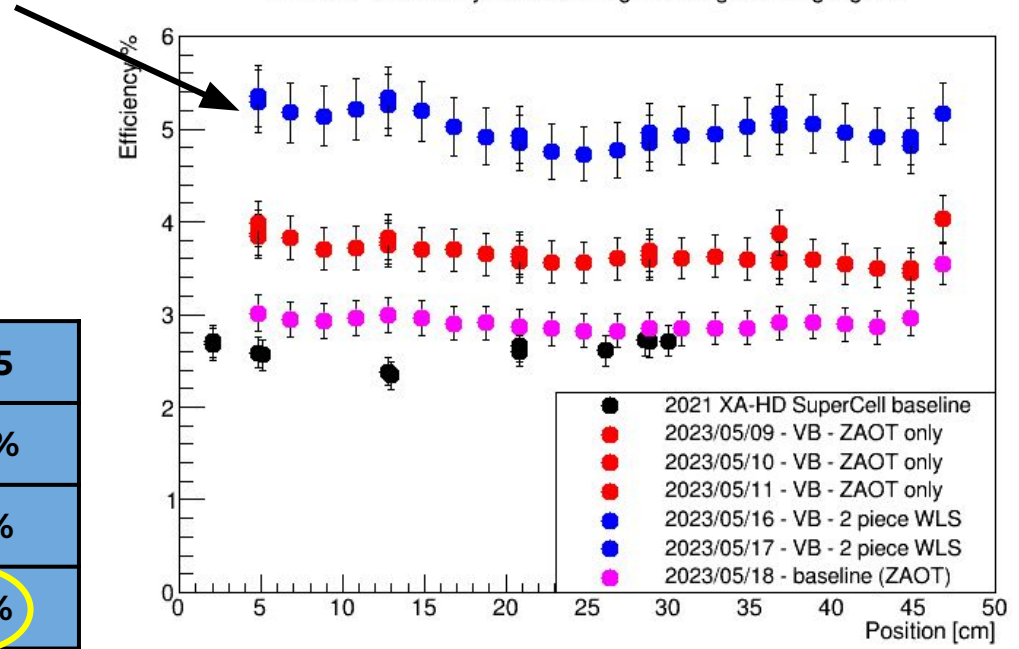
16-17/05/23 - 40° cut light guide, ZAOT only, G10 blocks



G2P p-DUNE LG with 40° cut

➤ PDE: + 37%

HPK G2P ZAOT only - increased light sealing + new light guide



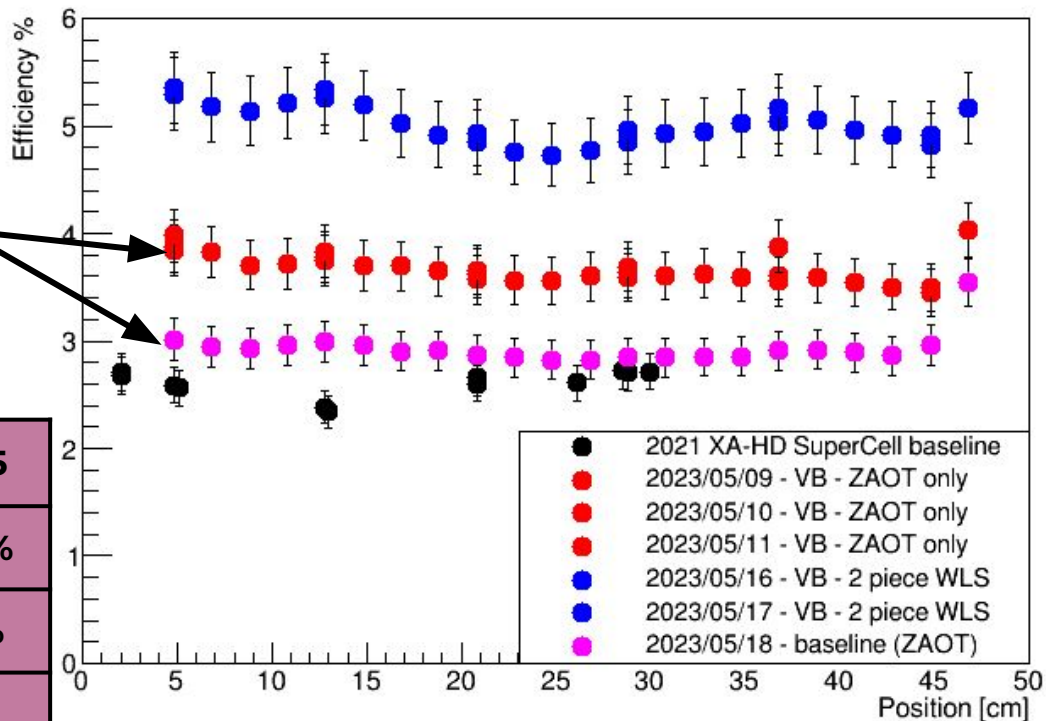
measure	baseline	10/05	16/05
avg PDE	2.51%	3.59%	4.93%
% wrt bl	-	+43%	+96%
% wrt 09/05	-	-	+37%

18-19/05/23 - Control measurement for G10 blocks

p-DUNE WLS-LG no cut: used the same bar as in previous meas.

- All ZAOT DF
- Removed G10 blocks to check their effect
 - confirmed their relevant effect (PDE: ~ -25%)

HPK G2P ZAOT only - increased light sealing + new light guide



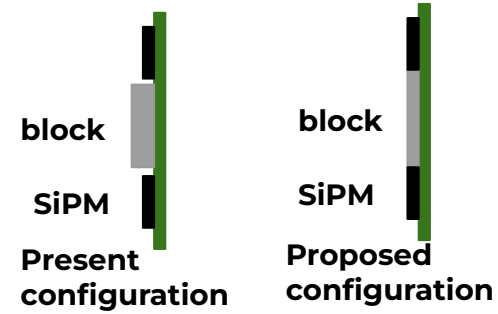
measure	bl	10/05	16/05	18/05
avg PDE	2.51%	3.59%	4.93%	2.86%
%wrt bl	-	+43%	+96%	+14%
%wrt ctrl	-	+26%	+72%	-

Conclusions

- We observed a **PDE increase when minimizing**
 - **SiPM-WLS distance**
 - **WLS-Vikuiti distance: → insert Vikuiti lined blocks between SiPMs.**This improves the WLS light-sealing and prevent photons to impinge onto the inactive SiPMs sides (see also Marcio's sim work)
- A **diagonal cut of the WLS-LG also improves the PDE**
 - **breaks the OP** bouncing back and forth from the short edges **reflecting the light onto the SiPMs**
 - **reduces the OP**
- The ZAOT DF perform slightly better than the OPTO when deployed in a FD1-XA, provided the pTP coating has the same performances → dedicated measurements in Pavia with monochromator
- The detailed simulations are an important tool and drove our work

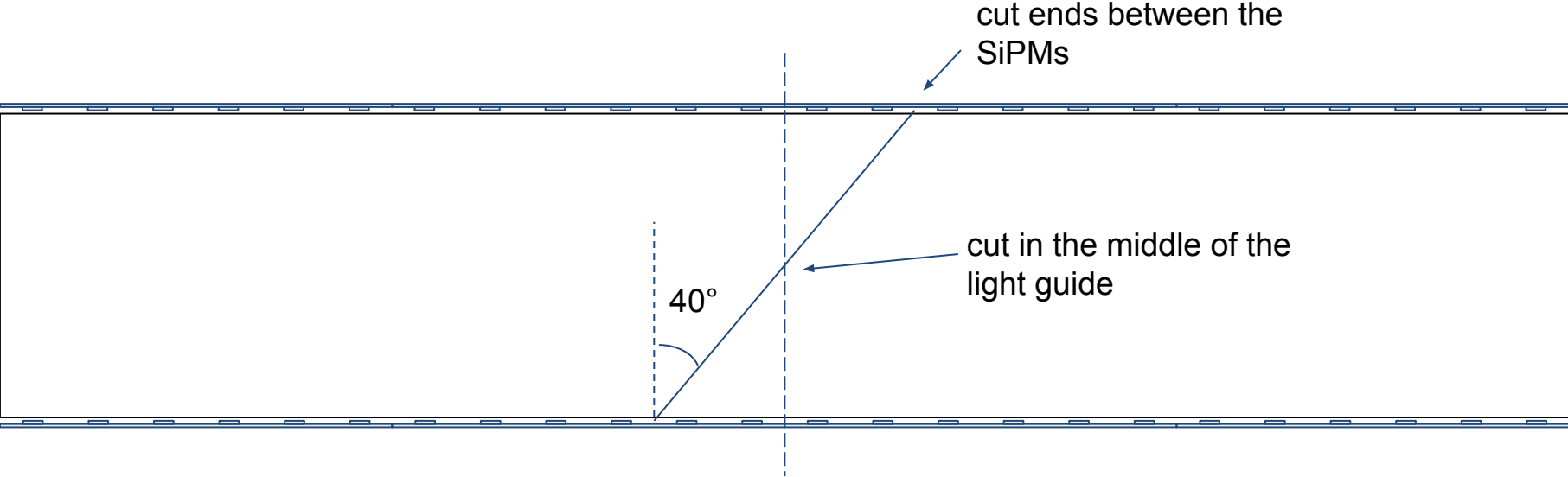
Recommendations for the FDI XA configuration

- Use the **widest possible WLS** within the SiPM-WLS tolerances.
- **Differentiate the WLS bars width for HPK and FBK** photosensors: Width difference 1.3 mm
- Use thinner (than BL design) spacer blocks
- **Fill the gaps between SiPMs** with G10 blocks
 - lined **with Vikuiti**,
 - **possibly flush with the SiPM surface**
- Adopt **WLS with one cut to break looping optical paths**
- Adjust the chromophore concentration in the WLS (minor)



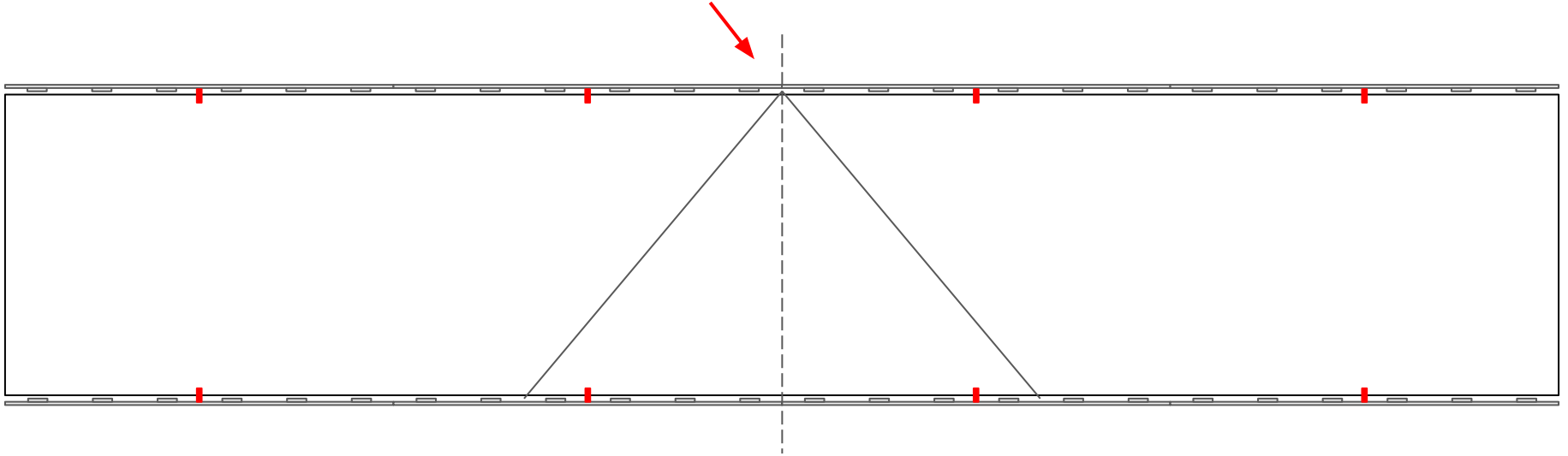
	HPK		FBK	
	ave	tol	ave	tol
Encapsulated SiPM thicken.	1.35	0.2	1.8	0.2
Die attach	-	-	0.3	0.2
SiPM height on top of the PCB	1.34	0.1	2.1	0.3
PCB thickness	1.6	0.15	1.6	0.16
Pin Protrusion	<0.5		<0.15	
SiPM-SiPM side gap	14	-	12.3	0.3
FBK WLS width w.r.t. HPK			-1.3	

light guide sketch



Backup

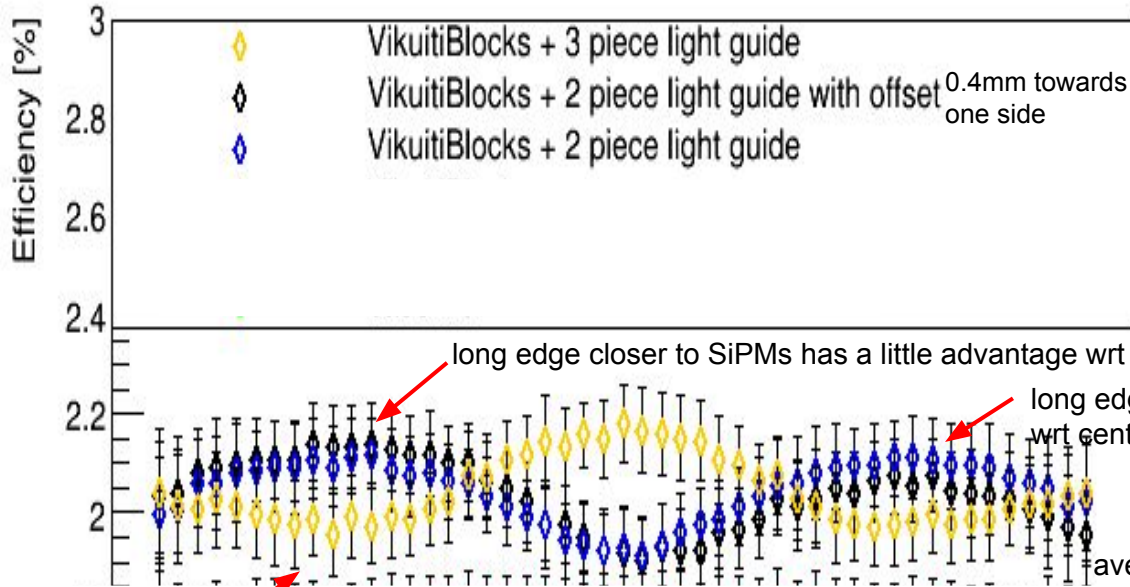
middle piece has no supports (in red) on one side



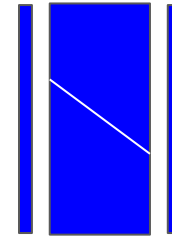
if we want at least 3 supports per piece, with 3 pieces we would need 9 supports

buoyancy

Supercell Scan - 0.5mm SiPM-WLS dist

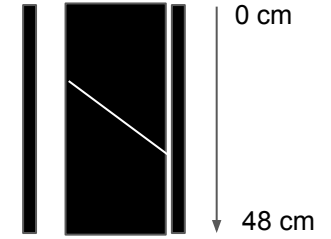


centered bar - blue curve



0.5mm gap at each side

buoyancy - black curve



total gap is 1mm for both sim runs

without taking into account the offset (buoyancy) from the center, the 3 piece bar performs the same as the 2 piece one (about +63% wrt baseline according to the sim)

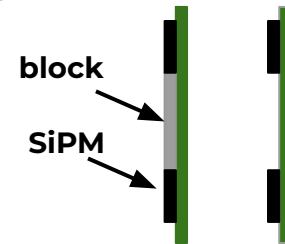
long edge more distant to SiPMs has a little disadvantage wrt centered bar

averaging, the two effects cancel, given the 2 piece geometry symmetry

the effect is small, even maximizing the edges close to the SiPM (3 piece geometry) the total gain would be O(1%)

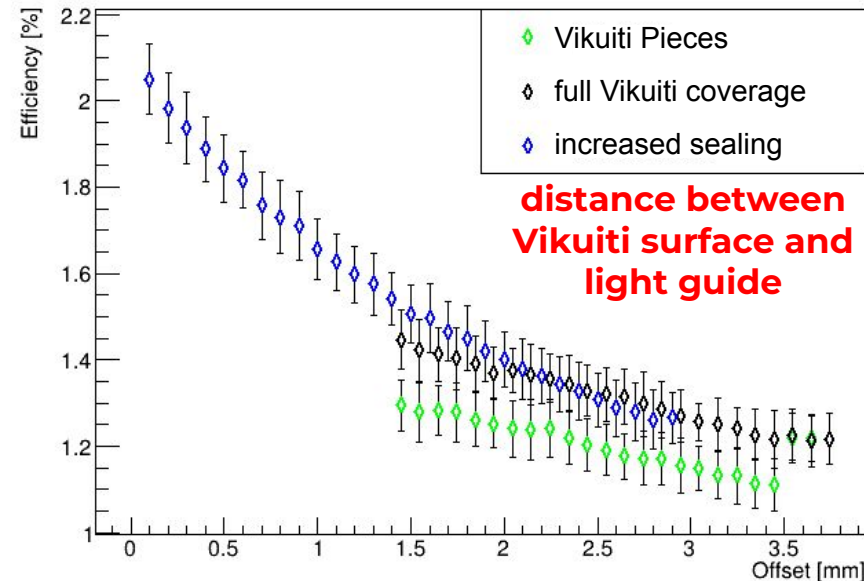
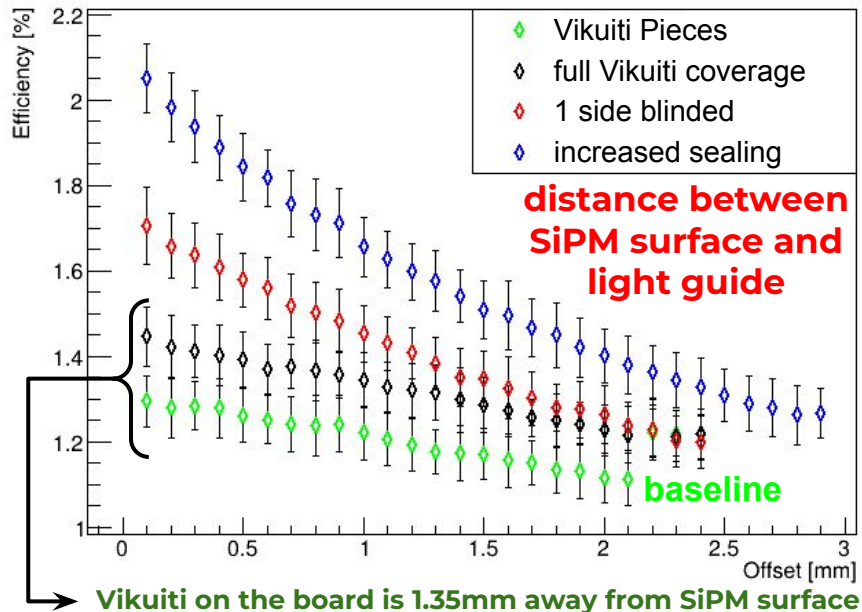
Simulation - distance between SiPMs and light guide

- **PDE is strongly dependent on the SiPM-Ig distance**
 - **distance of the Vikuiti reflector** seems to be the main factor
- simulated PDE offsetting the SMB wrt the light guide
 - SiPM and Vikuiti are integral with the PCB



SiPM Offset Scan

SiPM Offset Scan



Legend items of the previous plots

For all the simulations: Vikuiti on the mechanical frame.

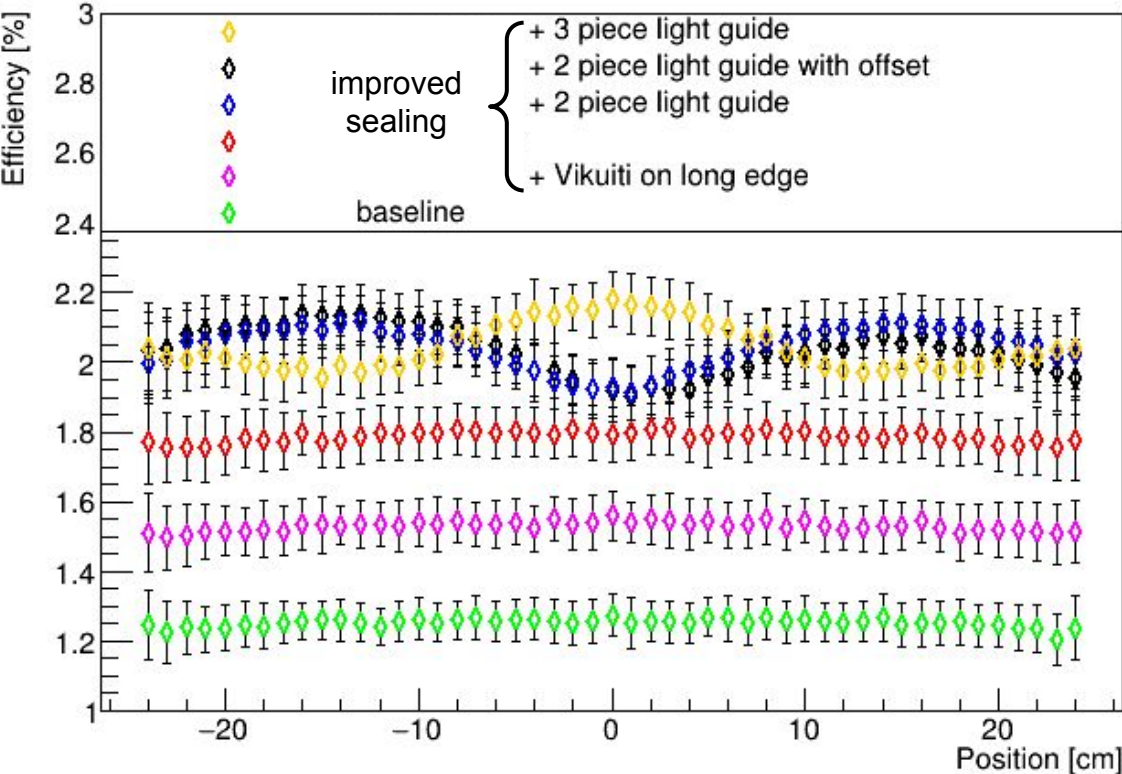
- Vikuiti Pieces = Vikuiti on SiPM PCBs as it currently is (holes for screws and inner side of the SiPM pins);
- Full Vikuiti coverage = Vikuiti on SiPM PCBs but without any hole;
- Increased sealing = G10 blocks placed between each SiPM and covered with Vikuiti → Vikuiti closer to the WLS bar without covering the SiPMs;
- 1 side blinded = Increased sealing + Vikuiti on one of the long edges of the WLS bar (SiPMs are hence partially covered).

Simulation - light guide configurations

- Cons: the cut causes a (minor) **disuniformity in the light collection** along Z
 - less increase in PDE near the cut
- **simulated different SC configs Z scans with the SiPM distance fixed at 0.5 mm**
 - then averaged all the Z-positions
- **this plot can vary a lot depending on the fixed variables**
 - SiPM distance
 - light guide attenuation length
 - ...

Simulation - light guide configurations

Supercell Scan - 0.5mm SiPM-WLS dist

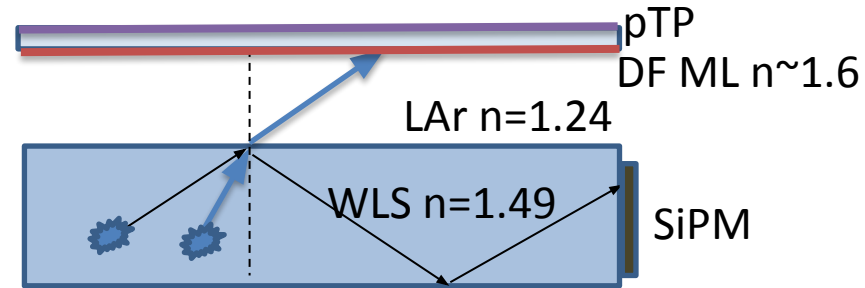


config	average PDE*	% wrt baseline
baseline	1.25	-
VB + VonLE	1.53	+22%
Vikuiti Blocks	1.79	+43%
VB + 2 piece WLS	2.04	+63%
VB + 2 piece offs	2.04	+63%
VB + 3 piece WLS	2.04	+63%

PDE enhancing

The two XA photon collection mechanisms:

- **Lightguiding (LG):** For $\theta > \theta_c$ ($=56^\circ$) pTP downshifted photons are trapped into the LG and guided to SiPM.
- **Dichroic Filters (DF):** For $\theta < \theta_c$ photons leave the lightguide and may reach the SiPM by multiple bounces onto the DF & reflectors



The work presented in the following

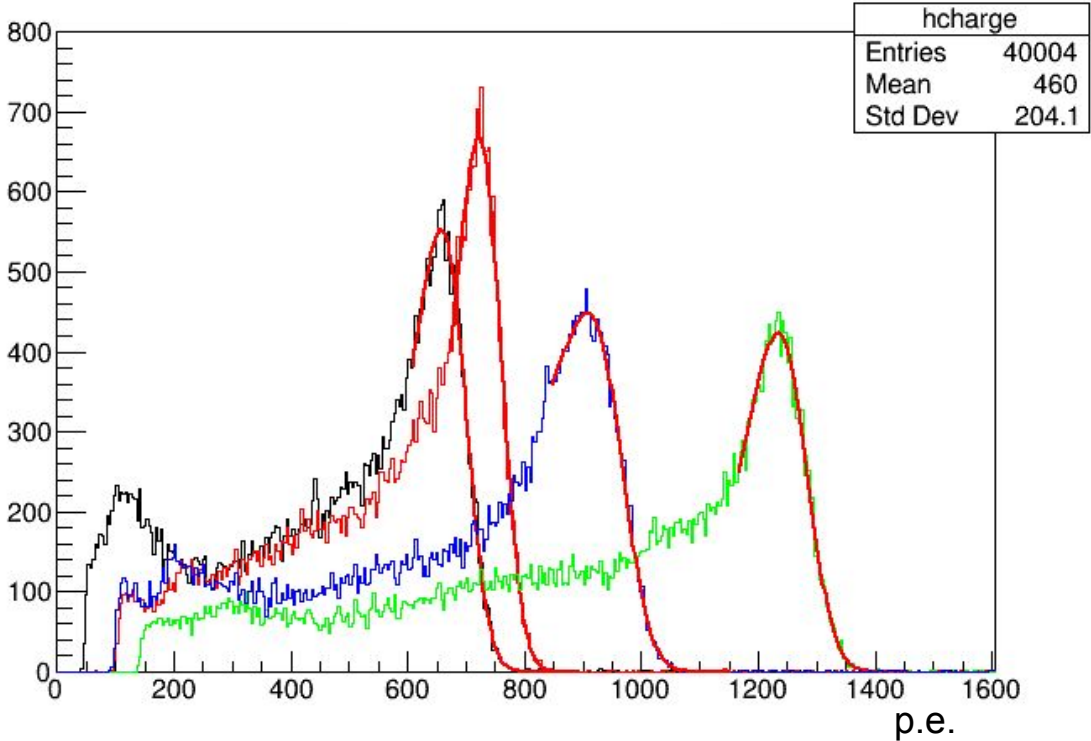
- enhances the **LG** mechanism, within the **FD1** mechanical & electrical constraints.
- assesses the **FD2 Module-0 DF** performances w.r.t to the **FD1-BL**

Alpha Spectra resolution, p.e. calibrated

- baseline
- p-DUNE WLS, NO G10 blocks, ZAOT
- p-DUNE WLS, G10 blocks, ZAOT
- WLS with cut, G10 blocks, ZAOT

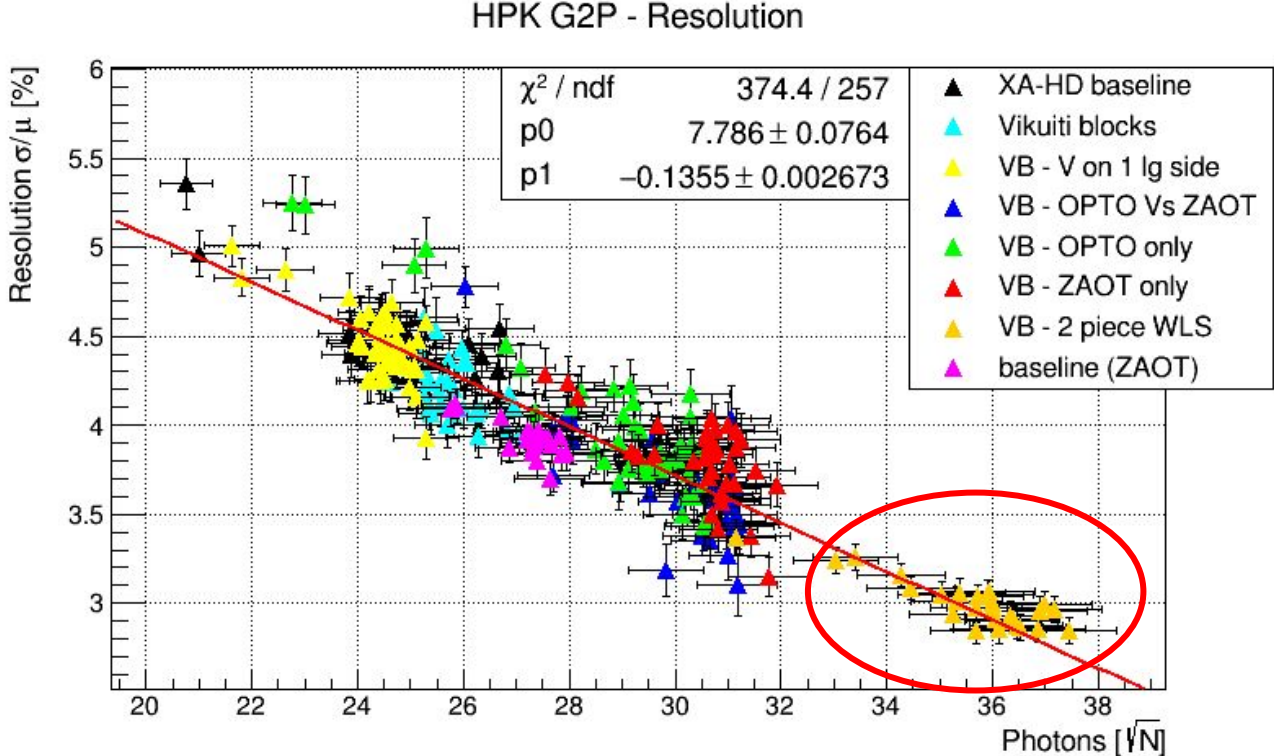
All taken in the middle of the 3rd dichroic filter

mu = 692.704 **sigma = 31.4929**
mu = 749.976 **sigma = 30.3693**
mu = 962.185 **sigma = 38.2959**
mu = 1272.26 **sigma = 38.0256**



Alpha Spectra resolution

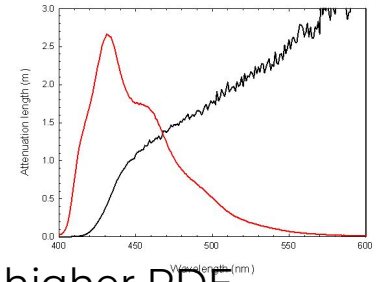
- The 2 pieces WLS Ig improves the energy resolution w.r.t. all the other configurations



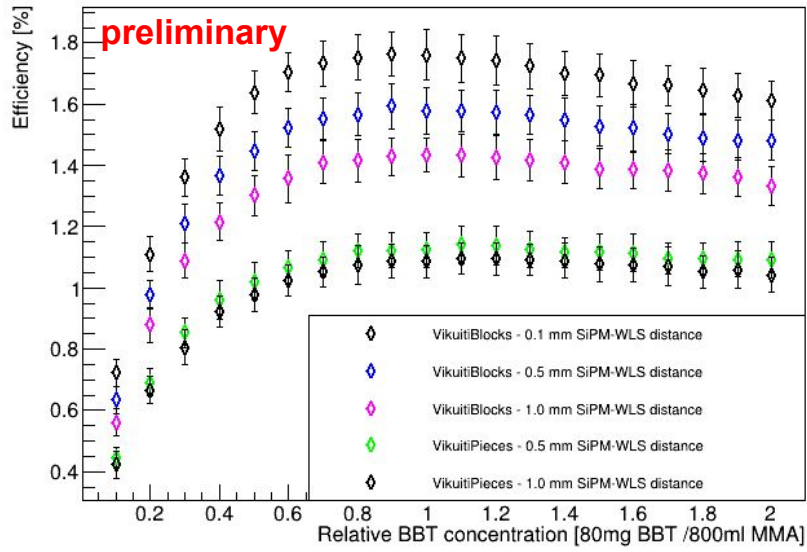
Simulation - WLS dye concentration (Attenuation length)

G2P UniMiB provided the **attenuation curve** of the **WLS**

- l_{att} depends on the chromophore concentration (Lambert-Beer law)
- **through simulation, different attenuation curves can be tested to obtain the optimal concentration for a given geometry**



BBT concentration scan

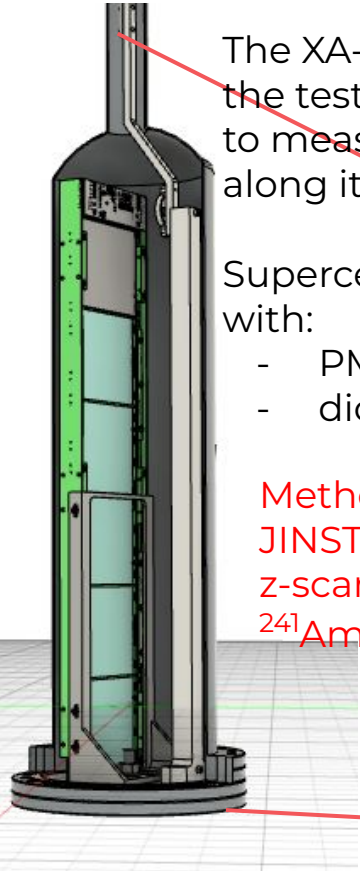
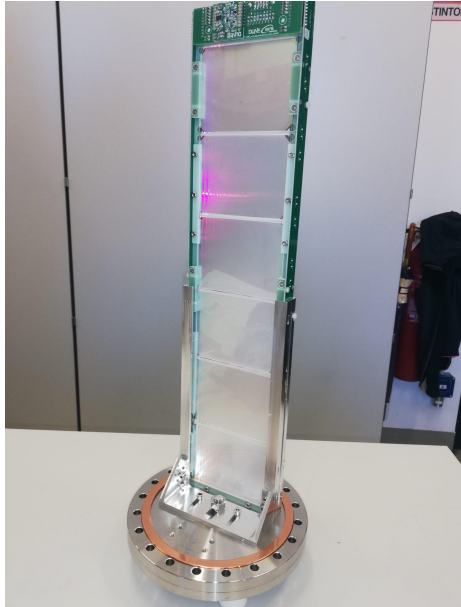


- higher light sealing leads to higher PDE
- light sealing increases the optical path
 - light can bounce back and forth
- a lower dye concentration corresponds to longer l_{att}
- the actual WLS is properly designed to optimize the FD1 PDE (maybe possible a 20% decrease of the chromophore)

→ an optimum is found at lower dye concentration when the optical path is higher

Setup to measure the XA-HD-SC PDE in LAr

The XA-HD-SC w. Cold FE circuit (top)



The XA-SC installed in the test chamber (~10 l) to measure the PDE along its z-axis.

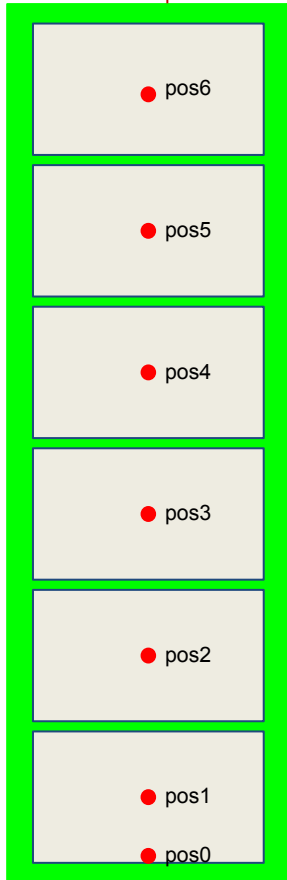
- Supercell equipped with:
- PMMA WLS (G2P)
 - dichroic filters

Method as published in JINST 16 (2021) 09027: z-scanning with an ^{241}Am exposed α source



Method & Data taking

pos-mu



z-scanning of the SC with the ^{241}Am α (5.480 MeV) source at the following positions:

1. **pos0**: (the lowest possible): ~ 2 cm above the flange.
2. **pos1, 2, 3, 4, 5, 6**: the center of each dichroic filter.
Acquired: $10^4 \times 4$ wfms; 20 μs length; ~ 5 μs pretrigger.
3. Source at the topmost position (~ 49 cm from the flange) and \sim out of LAr:
 - one **μ run** ($10^4 \times 4$ events; 20 μs , 5 μs pretrigger)
 - one **s.p.h.e. run** ($10^4 \times 8$ events; 20 μs length; 1.6 μs pretrigger)

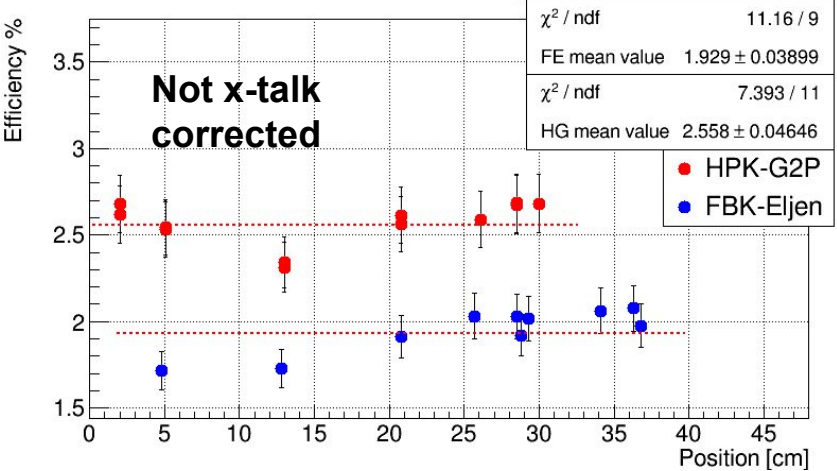
Source-to-dichroic filter distance: (55 +/- 1) mm.

Noise Run: $V_{\text{bias}} = V_{\text{bd}} - 1\text{V}$ for FFT and filter shape&cutoff definition

Results for the FDI XA baseline configuration

$$\epsilon = \frac{4\pi \cdot \alpha \text{ peak(ADC)}}{\text{s.ph.e.(ADC)} \cdot f_{int} \cdot LY_{LAR} \cdot En_{\alpha} \cdot q_{\alpha} \cdot \Omega}$$

HPK-G2P Vs FBK-Eljen



	SiPM PDE	XA PDE MiB Xtalk corr.	XA PDE CIEMAT Xtalk corr.
HPK & G2P	50%	2.2 (0.15)	2.51 (0.21)
FBK & G2P	50%	1.9 (0.14)	
FBK & Eljen	50%	1.7 (0.14)	1.56 (0.12)
SBND (HPK & G2P)	50%	2.9 (0.1)	

SBND: the SiPM distribution allowed the max. optical seal with Viquiti the LG (>50% of perimeter) C. Brizzolari et al 2021 JINST 16 P09027

→ efforts to improve the PDE for the FDI-XA (preserving the current mechanics)

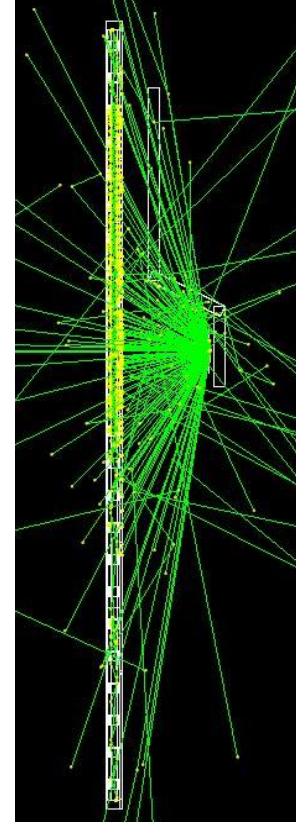
MC computed geometric acceptance

The knowledge of the solid angle is crucial for the PDE determination.

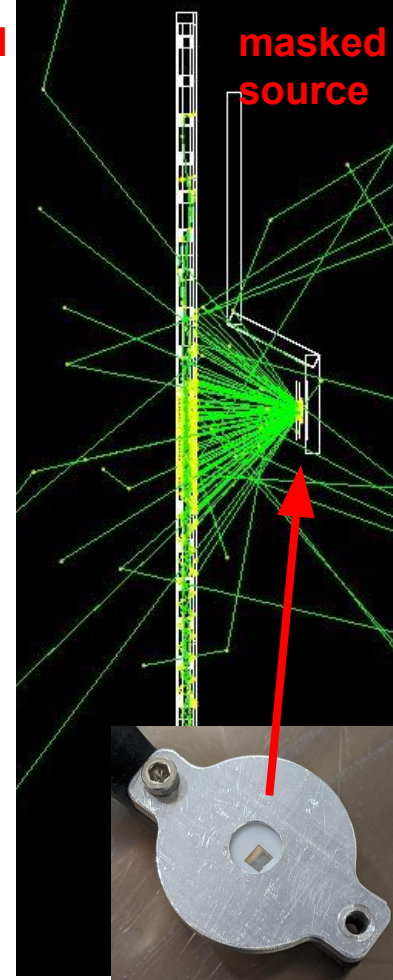
Solid angle computed via a geant4 simulation

- geometry takes into account also the source holder, the source arm and the teflon mask (in the first analytical simulation only the source holder arm was modeled)
- solid angle obtained from the ratio of photons hitting the pTP deposit over the scintillation photons
 - $\Omega = (\gamma_{\text{pTP}}/\gamma_{\text{scint}})*4\pi$

unmasked
source



masked
source



ZAOT vs OPTO: T measurements @ MiB

OPTO and ZAOT in Water

